INFORMATION DISCLOSURE CITATION

ATTY DOCKET NO.	APPLICATION NO.
P-US002-G-SC	10/677,548
APPLICANT(S)	
Adam L. Cohen	
FILING DATE	GROUP ART UNIT
October 1, 2003	1753

U.S. PATENT DOCUMENTS

*EXAMINER INITIAL		DOCUMENT NUMBER	DATE	NAME	CLASS	SUBCLASS	FILING DATE IF APPROPRIATE
/EW/	1	2,306,082	12/22/1942	C.O. Prest	204	18	
	2	3,240,685	03/15/1966	Leon I. Maissel	204	15	
	3	3,697,401	01/09/1970	Lucas, et al.	204	143	
	4	3,745,105	07/10/1973	Kosowsky, et al.	204	224	
	5	3,835,017	09/10/1974	Mentone, et al.	204	224	
	6	4,043,891	08/23/1977	Alkire, et al.	204	231	
	7	4,080,267	03/21/1978	Castellani, et al.	204	15	
	8	4,126,533	11/21/1978	Lukyanchikov, et al.	204	224	
	9	4,155,815	05/22/1979	Francis, et al.	204	15	
	10	4,187,553	02/05/1980	Ahn, et al.	365	8	
	11	4,294,669	10/13/1981	Lincoln, et al.	204	15	
	12	4,370,941	02/01/1983	Betty R. Belton	118	13	
	13	4,376,017	03/08/1983	Kendall D. Urion	204	15	
	14	4,404,080	09/13/1983	Hooshang Jahani	204	224	
	15	4,452,684	06/06/1984	Karl Palnik	204	206	
	16	4,537,647	08/27/1985	Clark B. Foster	156	245	
	17	4,764,449	08/16/1988	Lawrence C. Vanlseghem	430	162	
	18	4,770,754	09/13/1988	Meuldijk, et al.	204	224	
	19	4,921,583	05/01/1990	Sewell, et al.	204	15	
	20	4,954,192	09/04/1990	John T. Dziekan	156	154	
	21	4,985,116	01/15/1991	Mettler, et al.	156	656	
	22	5,190,637	03/02/1993	Henry Guckel	205	118	
	23	5,209,817	05/11/1993	Ahmad, et al.	156	643	
	24	5,271,822	12/21/1993	Nolan, et al.	205	122	
	25	5,378,583	01/03/1995	Guckel, et al.	430	325	

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/EW/	26	5,395,508	03/07/1995	Jolly, et al.	130	549	
	27	5,413,668	05/09/1995	Aslam, et al.	216	2	
	28	5,435,902	07/25/1995	Larry E. Andre, Sr.	205	67	
	29	5,478,699	12/26/1995	Blessington, et al.	430	308	
	30	5,501,784	03/26/1996	Lessmollmann, et al.	205	67	
	31	5,512,162	04/30/1996	Sachs, et al.	205	91	
	32	5,560,837	10/01/1996	Kenneth E. Trueba	216	27	
	33	5,605,614	02/25/1997	Etienne Bornand	205	50	
	34	5,614,075	03/25/1997	Larry E. Andre, Sr.	205	67	
	35	5,641,391	06/24/1997	Hunter, et al.	205	80	5/15/1995
	36	5,766,441	06/16/1998	Arndt, et al.	205	170	11/22/1996
	37	5,874,011	02/23/1999	Daniel Ehrlich	216	65	8/1/1996
	38	6,019,784	02/01/2000	Richard A. Hines	128	898	4/3/1997
	39	6,197,180	03/06/2001	Kevin W. Kelly	205	118	2/5/1997

FOREIGN PATENT DOCUMENTS

		DOCUMENT NUMBER	DATE	NAME	CLASS	SUBCLASS	Translation Yes/No
/EW/	40	DE 32 12 152 A1	10/13/1983	Neese, et al.	C25D	7/06	No
	41	JP 1-255682 A	12/10/1989	Takagi, et al.	C25B	15/00	No
	42	JP 04-318187 A	11/09/1992	Ikeda Takashi	C25D	5/02	No
	43	JP 59-191356 A	10/30/1984	Satoru Kishimoto	C25B	15/00	No

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		DOCUMENT NUMBER	DATE	NAME	CLASS	SUBCLASS	Translation Yes/No
/EW/	44	JP 07-022425 A	01/24/1995	Sumiaki Maruyama	H01L	21/321	No
/EW/	45	JP 61-210636 A	09/18/1986	Yoshio Koshikawa	C23C	18/18	Yes, Abstract ONLY
/EW/	46	GB 2 127 855 A	04/18/1984	Michael Arthur Richards	C25D	5/02	

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			OTHER DOCUMENTS *(Including Author, Title, Date, Pertinent Pages, Etc.)*
/EW/	47		John D. Madden, et al., "Three-Dimensional Microfabrication by Localized, Electrochemical Deposition", J. of Micro. Sys., March 1996, 5(1):24-32.
	48		Taylor, et al., "'Spatial Forming' A Three Dimensional Printing Process", IEEE, 1995, pgs. 203-208. no month
	49		Marques, et al., "Fabrication of High-Aspect-Ratio Microstructures on Planar and Nonplanar Surfaces Using a Modified LIGA Process", December 1997, 6(4):329-336.
	50		Kumar, et al., "Features of gold having micrometer to centimeter dimensions can be formed through a combination of stamping with an elastomeric stamp..." Appln. Phys. Lett. , July 1993, 63(14): 2002-2004.

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